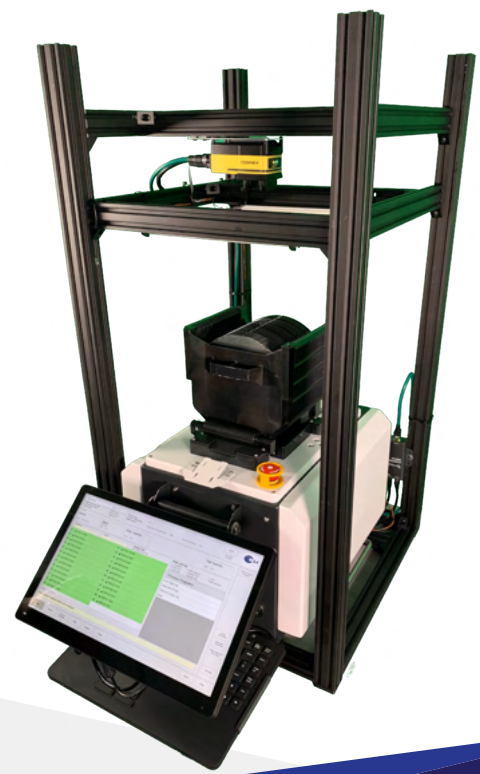


AUTOMATED AI BATCH WAFER EDGE INSPECTION

IDWR-EDGE



SUPPLIERS TO THE SEMICONDUCTOR INDUSTRY



DESCRIPTION



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EMU Technologies Batch Wafer Edge Inspection system combines our Batch ID Reader and Cognex InSight ViDi AI Inspection system to provide an ultra high-throughput and extremely versatile wafer edge inspection solution.

The equipment performs a batch align and read cycle to read lasermarks and/or datamatrix tags on each wafer.

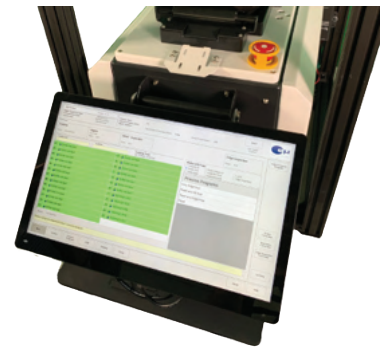
The equipment then rotates wafers using the batch aligner for edge defect inspection using a Cognex D905 camera.

An algorithm is trained to identify edge defects, which is deployed to the D905 camera as a job.

The machine can be connected to the host with SECS/GEM, providing a Pass/Fail result for each wafer in the Lot.

Defective wafer images are displayed on the user interface for analysis, if required.

With a typical cycle time of 3 minutes for a Batch ID Read and Batch Inspection, the machine can process up to 500wph with reading and 1500wph for edge inspection only.



FACILITY REQUIREMENTS

100/240V AC – 50-60Hz - 2A

SPECIFICATIONS

Throughput: 500wph

Footprint: L650 x W 500 x H 1000mm

OPTIONAL EXTRAS

True Edge Inspection
Frontside Exclusion Zone Inspection
Backside Exclusion Zone Inspection



This tool has been designed under license from Recif Technologies using the same design principles, materials and kinematics as were used in the original equipment and wafer fabs around the world.